

Docket No.: F06-436-US

FUJI.081

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application

Mineo HIRAMATSU, et al.

Serial No.: 10/569,838

Group Art Unit: Unknown

Filed: February 24, 2006

Examiner: Unknown

For: **METHOD FOR PRODUCING CARBON NANOWALLS, CARBON NANOWALL, AND APPARATUS FOR PRODUCING CARBON NANOWALLS**

Honorable Commissioner of Patents  
Alexandria, Virginia 22313-1450

**INFORMATION DISCLOSURE STATEMENT**

Sir:

Under the provisions of 37 CFR §1.97 through §1.98 and pursuant to applicant's duty of disclosure under 37 CFR §1.56, applicant respectfully brings the following documents, cited in the Japanese Office Action in a counterpart foreign application, and listed on the attached form PTO-1449, to the attention of the Examiner in charge of the above-identified application. Copies of the listed documents (including English language Abstracts) are provided herewith for the convenience of the Examiner.


In compliance with the requirements of 37 CFR §1.98(a)(3), as a concise statement of relevance, as it is presently understood by the individual designated in 35 U.S.C. §1.56(c) most knowledgeable about the content of the information, the undersigned attorney of record submits a partial translation of an official action by a foreign examiner in which the references were cited. The relevance to the pending U.S. patent application is that the references were cited in a foreign patent application on the same subject matter. However, no independent analysis of the references, the accuracy of the statement of the foreign examiner or the claims of the foreign application under the laws of that country of the United States relative to the subject matter claimed in the present application has been made, the present understanding of the contents thereof by the undersigned being based on the translation of the foreign examiner's comments submitted herewith.

This citation does not constitute an admission that the references are relevant or material to the claims. They are only cited as constituting related art of which the applicant is aware.

It is respectfully requested that the listed references be considered by the Examiner and formally made of record in this application.

Please charge any deficiencies in fees and credit any overpayment of fees to Attorney's Deposit Account No. 50-0481.

Respectfully submitted,



Sean M. McGinn

Registration No.: 34,386

Date: \_\_\_\_\_

4/23/07

**MCGINN INTELLECTUAL PROPERTY  
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<b>INFORMATION DISCLOSURE CITATION</b> (Use several sheets if necessary)				Docket Number (Optional) <b>F06-436-US</b>		Application Number <b>10/569,838</b>		
				Applicant(s) <b>Mineo HIRAMATSU, et al.</b>				
				Filing Date <b>February 24, 2006</b>		Group Art Unit <b>Unknown</b>		
<b>U.S. PATENT DOCUMENTS</b>								
*EXAMINER INITIAL	REF	DOCUMENT NUMBER		NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
<b>U.S. PATENT APPLICATION PUBLICATIONS</b>								
*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
<b>FOREIGN PATENT DOCUMENTS</b>								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
		2003-159699	06/03/2003	Japan			ABS	
		2003-171107	06/17/2003	Japan			ABS	
		2003-221217	08/05/2003	Japan			ABS	
<b>OTHER DOCUMENTS</b> (Including Author, Title, Date, Pertinent Pages, Etc.)								
		Japanese Office Action dated December 27, 2006, with partial english language translation						
EXAMINER				DATE CONSIDERED				
<b>EXAMINER:</b> Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								